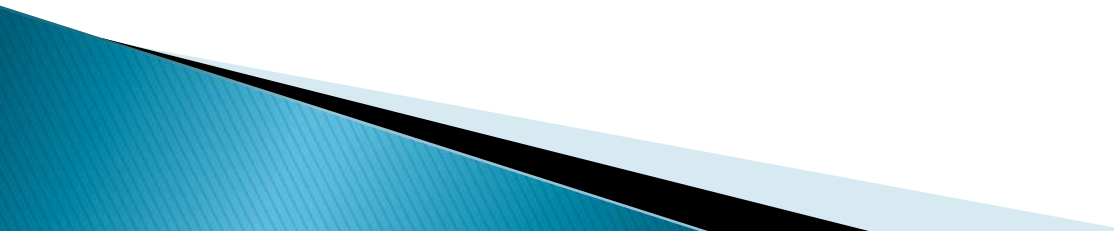


Band structure and electrical conductivity in semiconductors

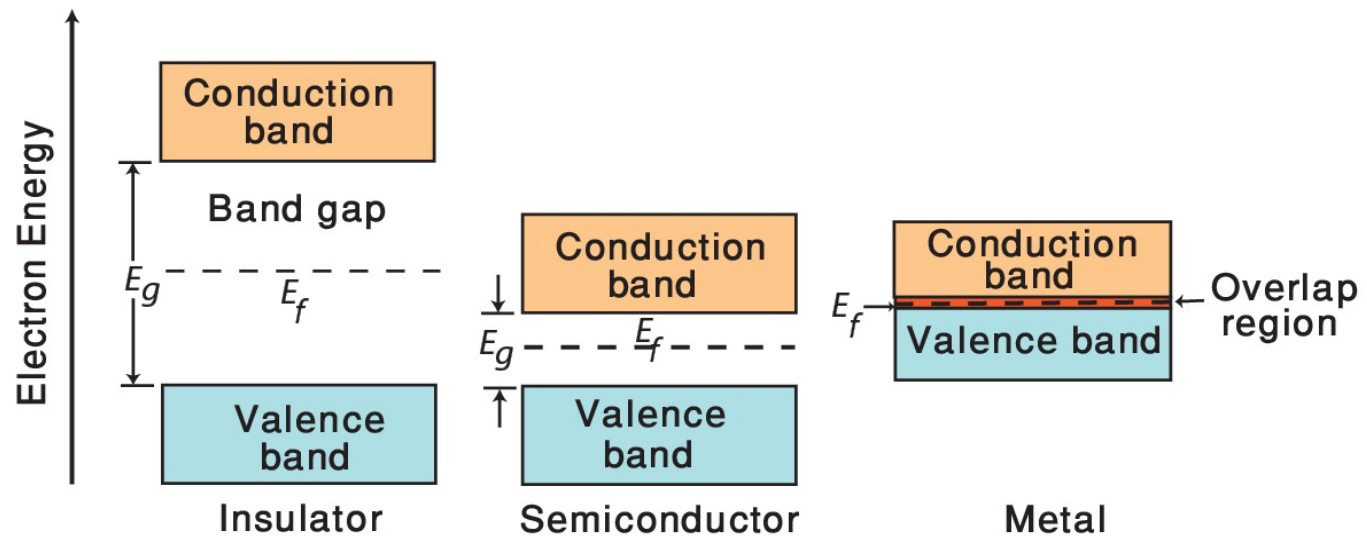
Amrozia Shaheen

Outline

- ▶ Semiconductors and their types.
 - ▶ Energy band gap.
 - ▶ Conduction in intrinsic and extrinsic semiconductors.
 - ▶ Experimental setup.
 - ▶ Results.
- 

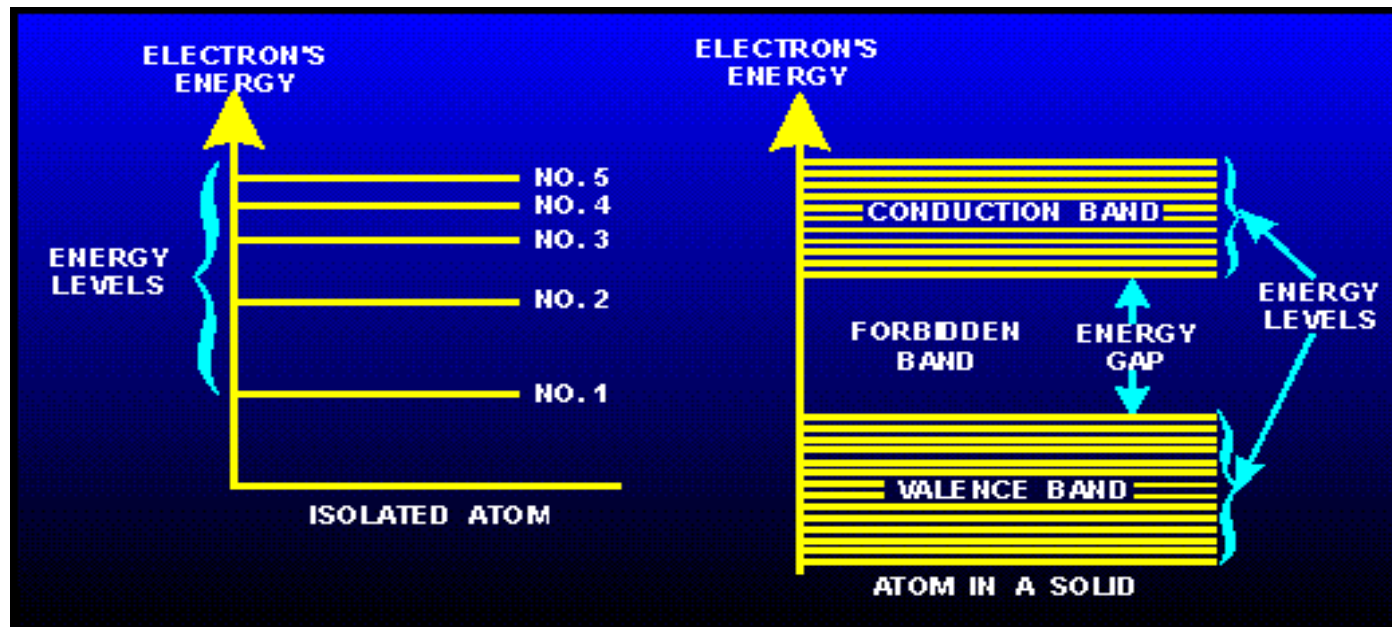
Semiconductors

- ▶ Semiconductors are materials in which both electrons and holes contribute to the conduction process. According to band theory of solids, semiconductors possess a band gap.



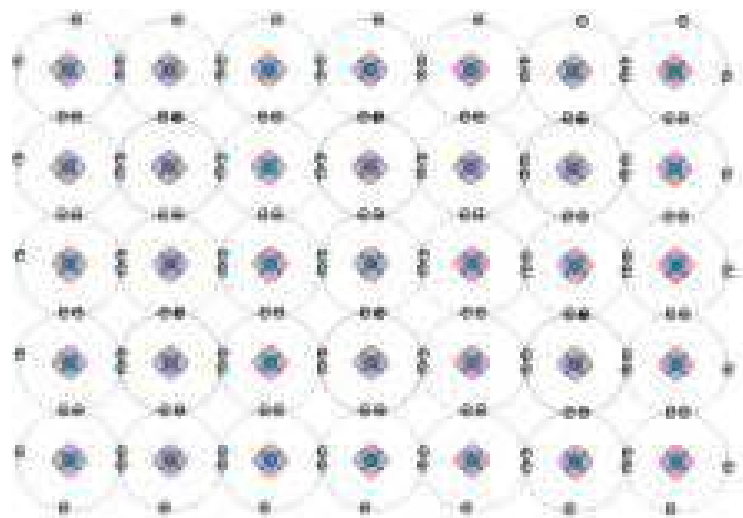
Energy band gap

- ▶ Energy band gap is a region in solids where no electron states can exist.
- ▶ Manifestation of the discrete character of basic atomic states.

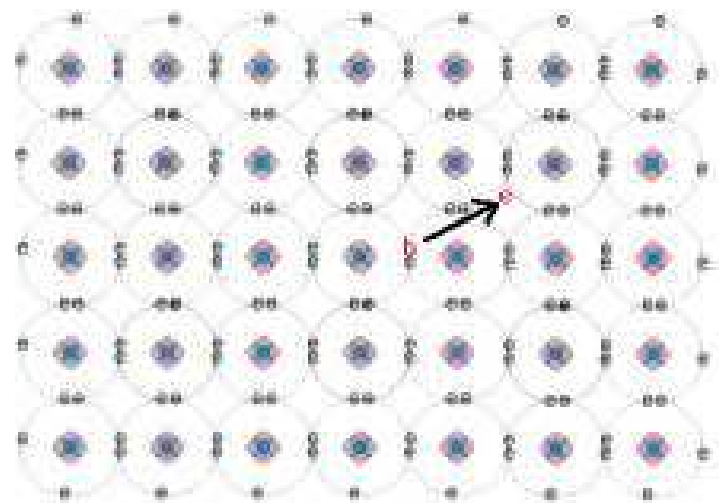


Energy band gap

- ▶ Ionization energy required to generate the electrons and holes.



insulating crystal before ionizing event



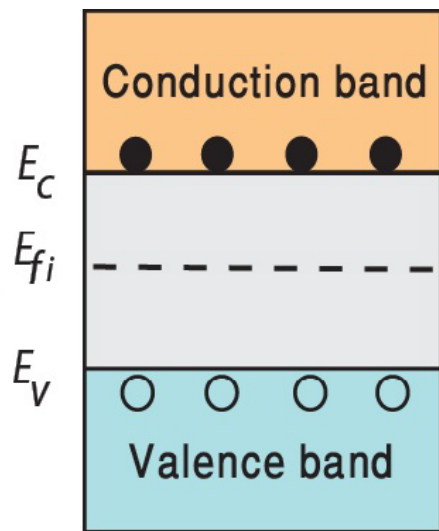
ionization event to give two mobile charge carriers

Semiconductor types

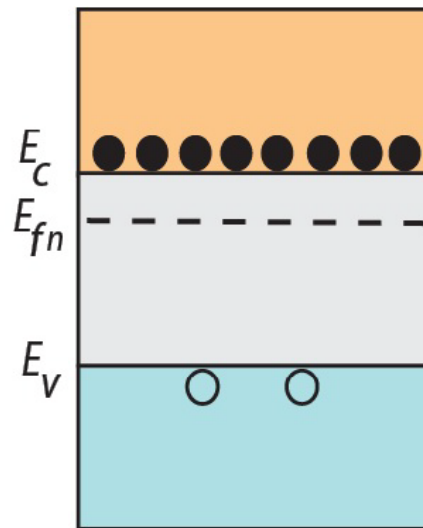
- ▶ An **intrinsic semiconductor** is a pure semiconductor having no impurities and equal numbers of excited electrons and holes, i.e., $n = p$.
- ▶ A semiconductor in which doping has been introduced, thus changing the relative number and type of free charge carriers, is called an **extrinsic semiconductor**.

Semiconductor types

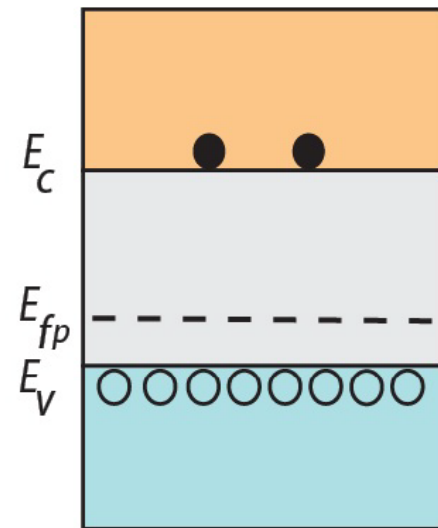
- ▶ If the conduction electrons are the majority carriers that is an n-type semiconductor and the holes for the p-type semiconductor.



(a)



(b)



(c)

Intrinsic semiconduction

- ▶ Thermally or optically excited electron's contribution to the conduction is called intrinsic semi conduction.

$$\sigma = n_e q_e \mu_e + n_h q_h \mu_h$$

- ▶ The electron density from bottom to the top of conduction band is

$$n_e = \int_{E_c}^{\infty} g(E) f(E) dE.$$

Intrinsic semiconduction

- Density of state is,

$$g(E) = \frac{(\sqrt{2})m_e^{*3/2}}{\pi^2\hbar^3} \left(E - E_c\right)^{1/2}.$$

- Probability of an electronic state of energy E being occupied by an electron is,

$$f(E) = \frac{1}{1 + \exp\left(\frac{(E - E_f)}{k_B T}\right)}.$$

$$f(E) \approx \exp\left(-\frac{E - E_f}{k_B T}\right).$$

Intrinsic semiconduction

- ▶ Electron and holes concentrations are,

$$n_e = N_c \exp\left(\frac{-(E_c - E_f)}{k_B T}\right),$$

$$n_h = N_v \exp\left(\frac{-(E_f - E_v)}{k_B T}\right),$$

$$N_v = 2 \left(\frac{m_h^* k_B T}{2\pi \hbar^2} \right)^{3/2}.$$

$$N_c = 2 \left(\frac{m_e^* k_B T}{2\pi \hbar^2} \right)^{3/2},$$

Intrinsic semiconduction

- ▶ In intrinsic semiconductor, $n_e = n_h$, so charge carrier concentration is,

$$n_i = \sqrt{n_e n_h} = \left(N_c N_v \right)^{1/2} \exp \left(\frac{-E_g}{2k_B T} \right),$$

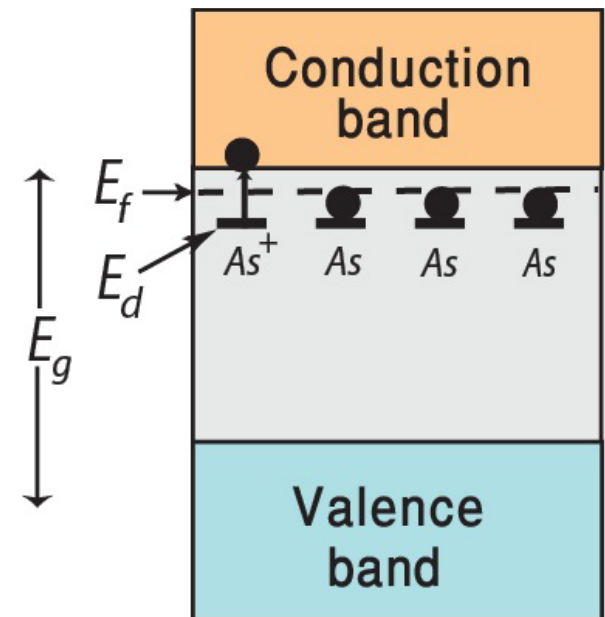
- ▶ Where, $E_g = E_c - E_v$ is the energy band gap, and intrinsic conductivity is,

$$\sigma = C T^{3/2} q_e \left(\mu_e + \mu_h \right) \exp \left(\frac{-E_g}{2k_B T} \right).$$

Extrinsic semiconduction

- ▶ In extrinsic semiconductor $N_d > n_i$, so the conductivity depends on carrier concentration and mobility
- ▶ Temperature dependence of carrier concentration
- ▶ Ionization regime: The electron concentration is given as,

$$n_e = \left(\frac{1}{2} N_c N_d \right)^{1/2} \exp \left(-\frac{\Delta E}{2k_B T} \right),$$



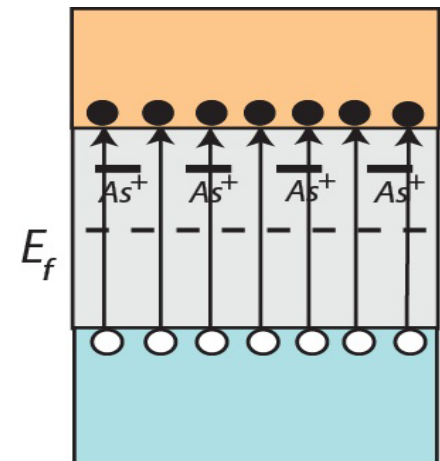
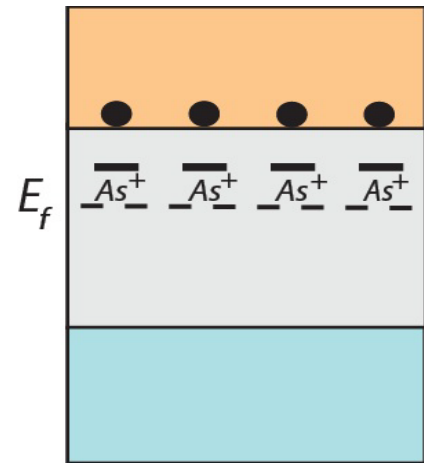
Temperature dependence of carrier concentrations

- ▶ **Extrinsic regime:** The electrical conductivity is,

$$\sigma = qn\mu,$$
$$n = N_d \simeq \text{constant}$$
$$\sigma = T^\alpha.$$

- ▶ **Intrinsic regime:** Doping importance is lost here and material behaves as an intrinsic semiconductor with,

$$n_i = CT^{3/2} \exp\left(\frac{-E_g}{2k_B T}\right),$$



Temperature dependence of mobility

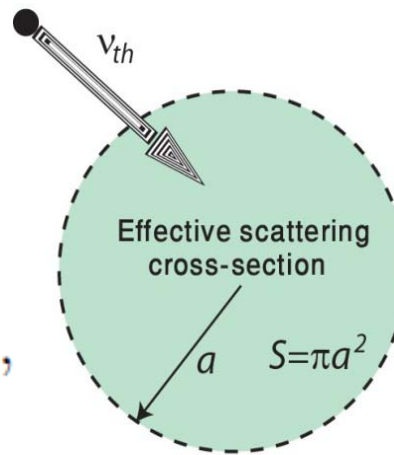
- ▶ **High temperature:** Electrons in C_B or C_V suffer collision with the impurity ion. The mean free time between scattering event and mobility is,

$$\tau = \frac{1}{Sv_{th}N_s}.$$

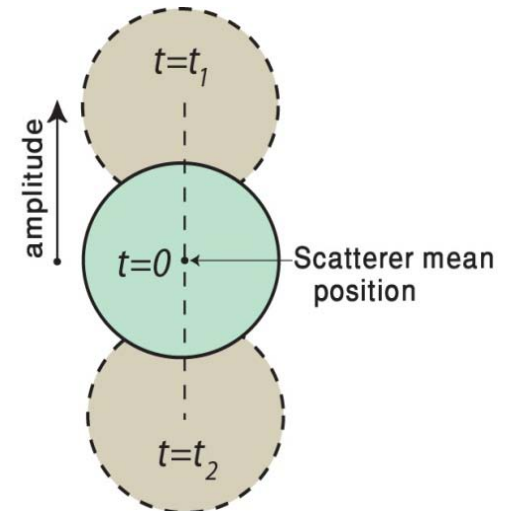
$$\mu = \frac{e\tau}{m_e^*}.$$

$$\tau_L = \frac{1}{Sv_{th}} \propto \frac{1}{T^{3/2}} = T^{-3/2},$$

$$\mu_L \propto T^{-3/2}.$$



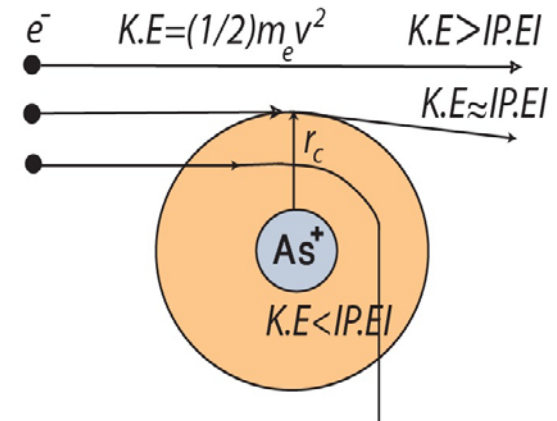
(a)



(b)

Temperature dependence of mobility

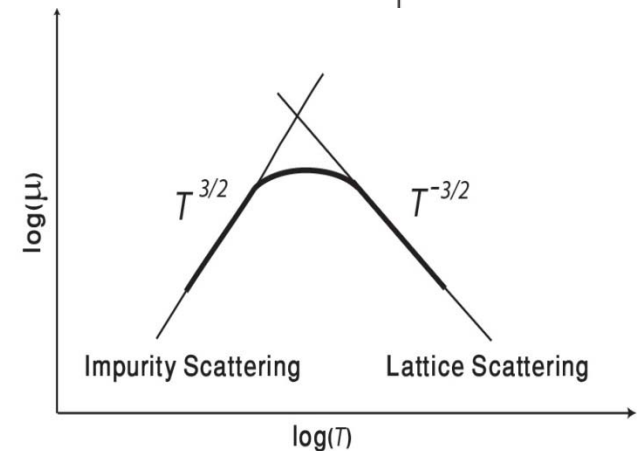
- ▶ **Low temperature:** Electron scattering is done by interaction with the ionized impurity.
- ▶ $K.E > |P.E|$, electron moves straight.
- ▶ $K.E < |P.E|$, electron is deflected.
- ▶ $K.E \approx |P.E|$,



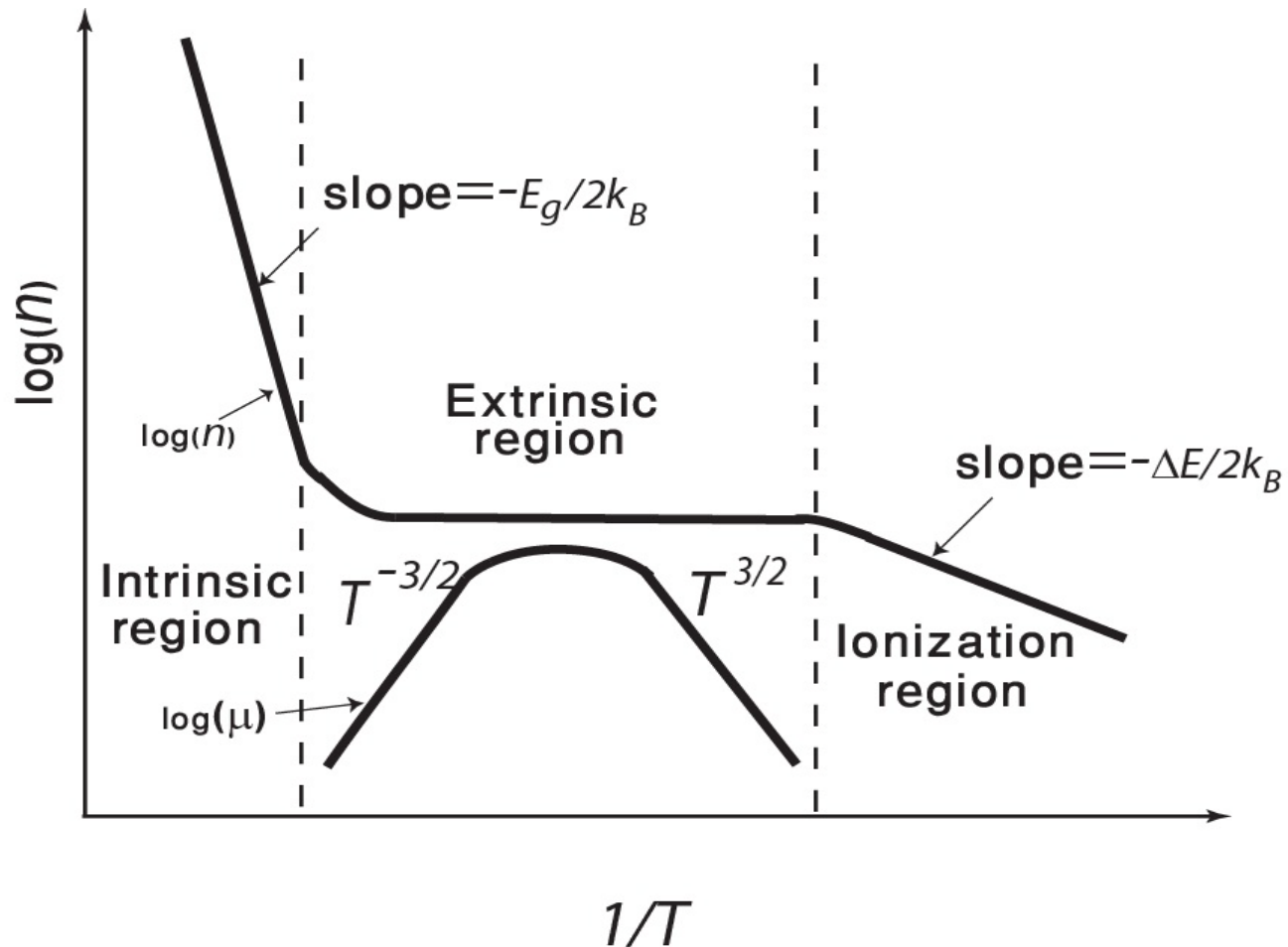
$$\frac{3}{2}k_B T = \frac{e^2}{4\pi\epsilon_0\epsilon_r r_c^2},$$

$$S = \pi r_c^2,$$

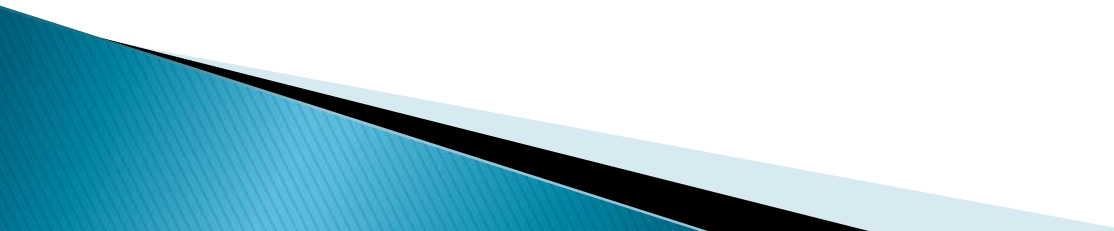
$$\mu_I \propto \frac{T^{3/2}}{N_I}$$



Temperature dependence of conductivity

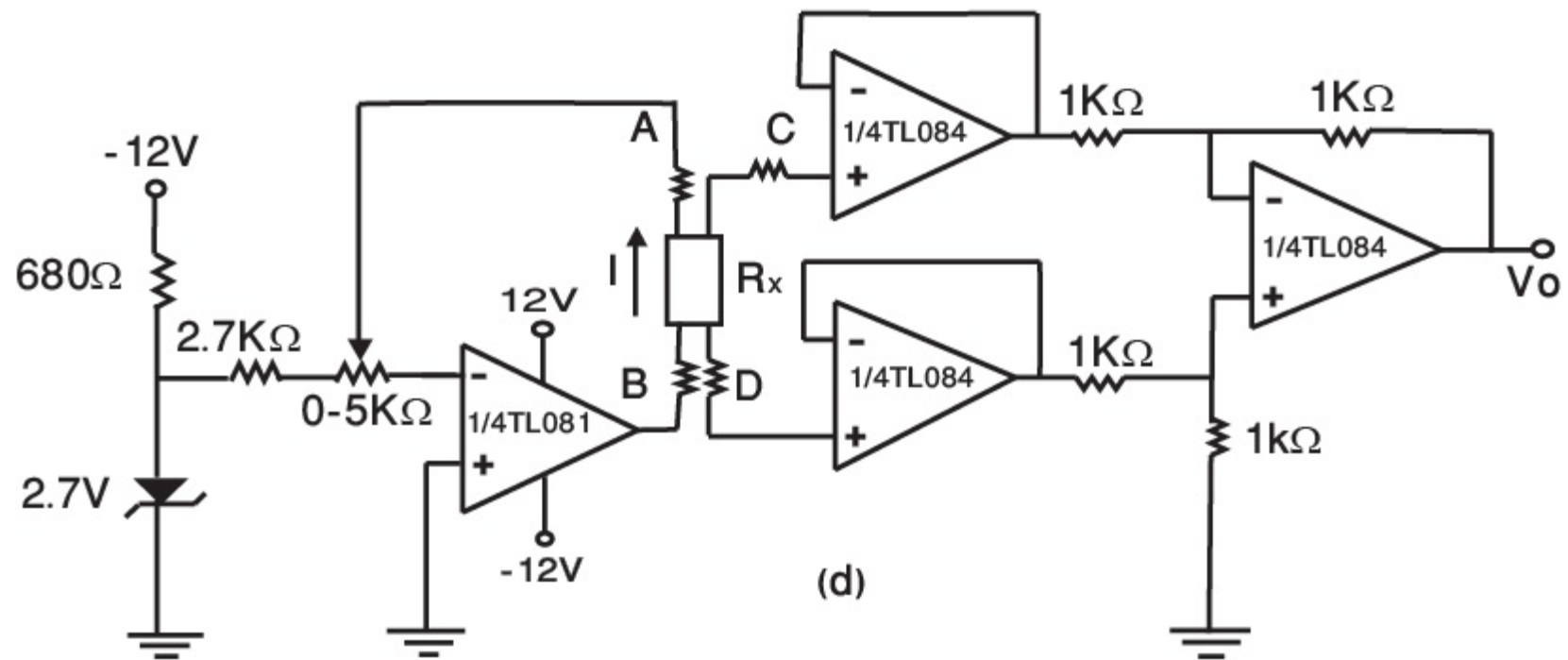


Experiment

- ▶ **Purpose**
 - ▶ Calculate the energy band gap for doped Si and pure Ge.
 - ▶ Calculate the temperature dependent coefficient of the majority carriers.
 - ▶ **Important parameters**
 - ▶ Resistance measurement.
 - ▶ Achieving high and low temperature regimes.
 - ▶ Temperature control.
- 

Resistance measurement

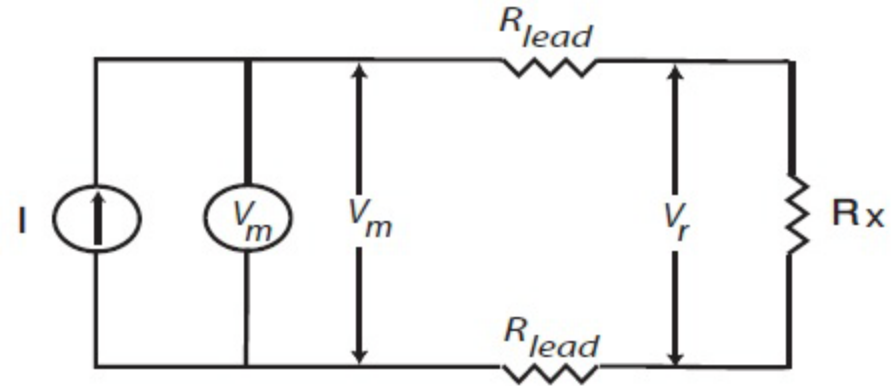
- ▶ The resistance of the semiconductor sample is measured by the four-probe technique.



Resistance measurement

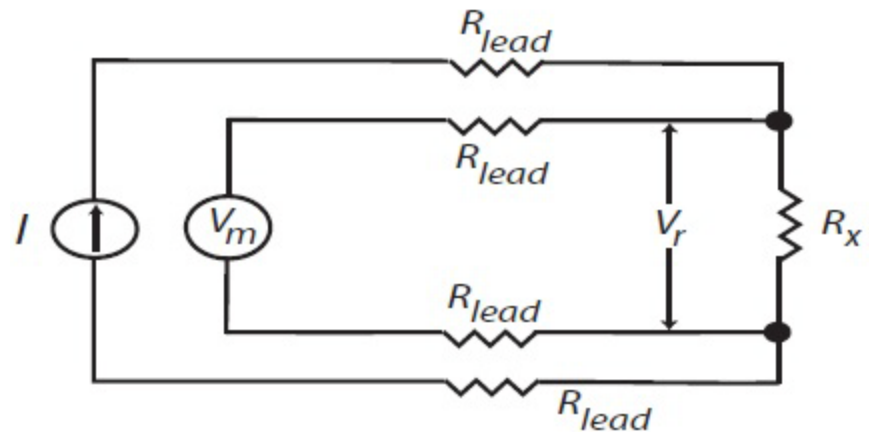
Two-probe method

$$\begin{aligned}\text{Measured resistance} &= \frac{V_m}{I} \\ &= R + (2 * R_{lead})\end{aligned}$$



Four-probe method

$$\begin{aligned}\text{Measured resistance} &= \frac{V_m}{I} \\ &= \frac{V_r}{I}\end{aligned}$$



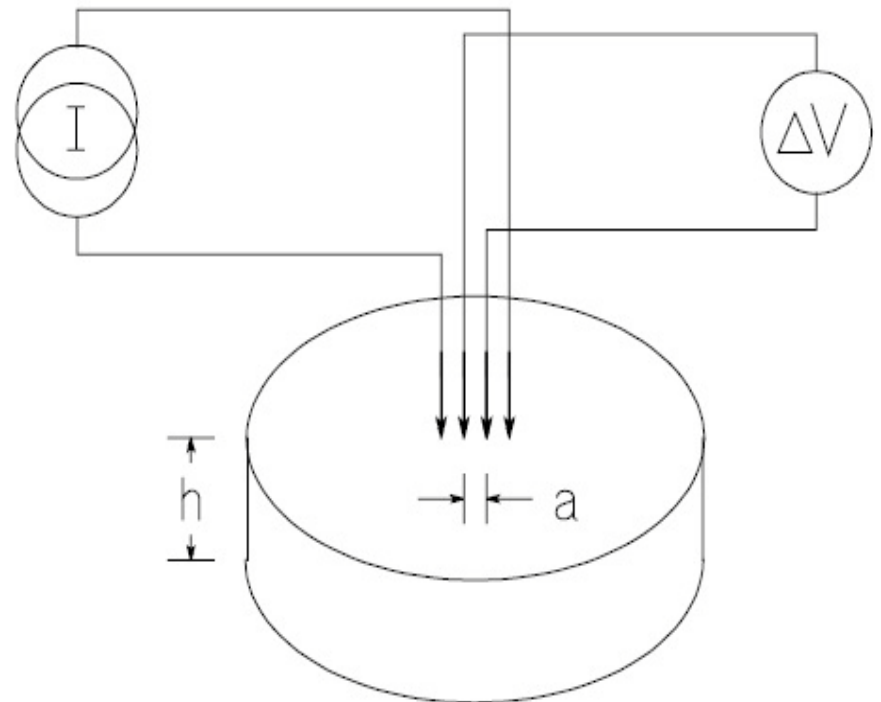
Resistance measurement

- ▶ The resistivity of a bulk sample in which $h \gg a$ is,

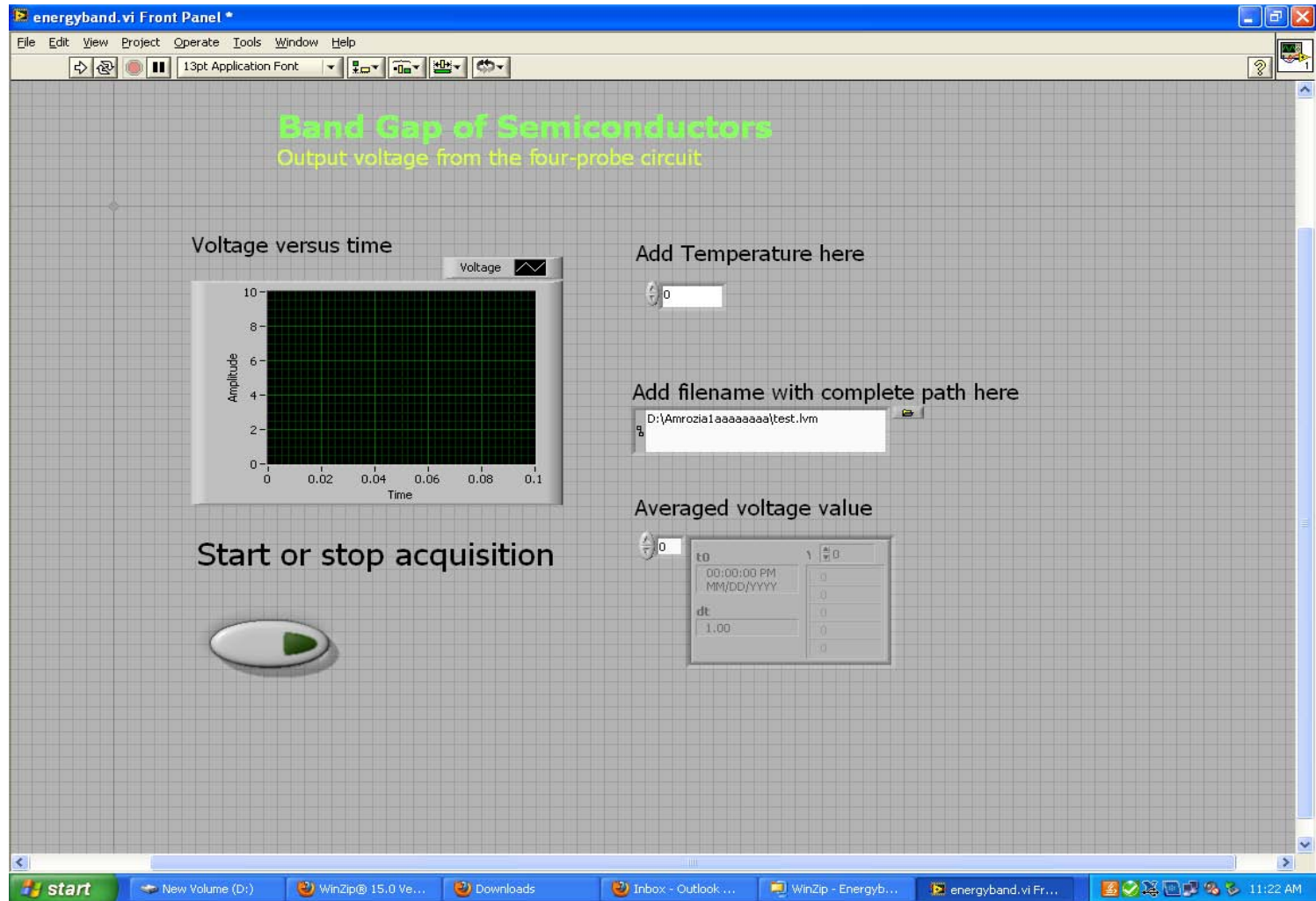
$$\rho = 2\pi a \left(\frac{\Delta V}{I} \right)$$

- ▶ For thin sheets having $h \ll a$, resistivity is,

$$\rho = \frac{\pi}{\ln(2)} h \left(\frac{\Delta V}{I} \right)$$



Resistance measurement



Low and high temperatures

- ▶ **Low temperature** is achieved using Liquid nitrogen that is poured into the flow cryostat.
- ▶ **High temperature** is attained by passing current through a heater wire wound around the sample cell.



Low and high temperatures

- ▶ **Heater calculations**

Nicrome wire (36)

Resistance= $42.7\Omega/\text{m}$.

Resistance of the used wire= $42.7*3=128.1\Omega$.

Applied voltage= 100 V AC .

Power= 78.1 .

- ▶ **Cryostat dimensions**

Length= 12 inches .

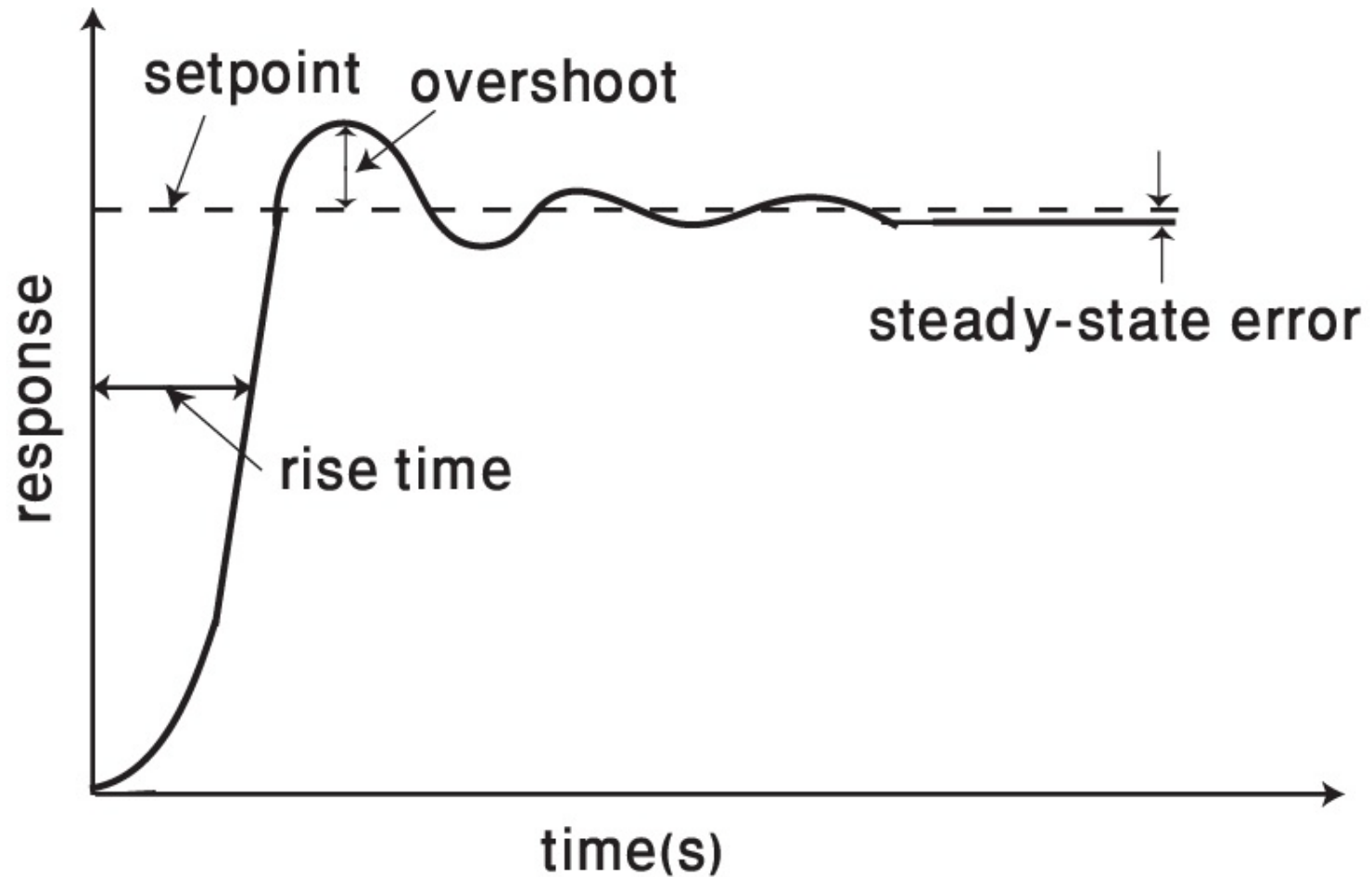
Diameter= 20mm .

Temperature measurement

- ▶ The temperature of the sample is measured by using a K-type thermocouple and controlled temperature is attained by a multi-zone controller (CN1504-TC).



Temperature measurement



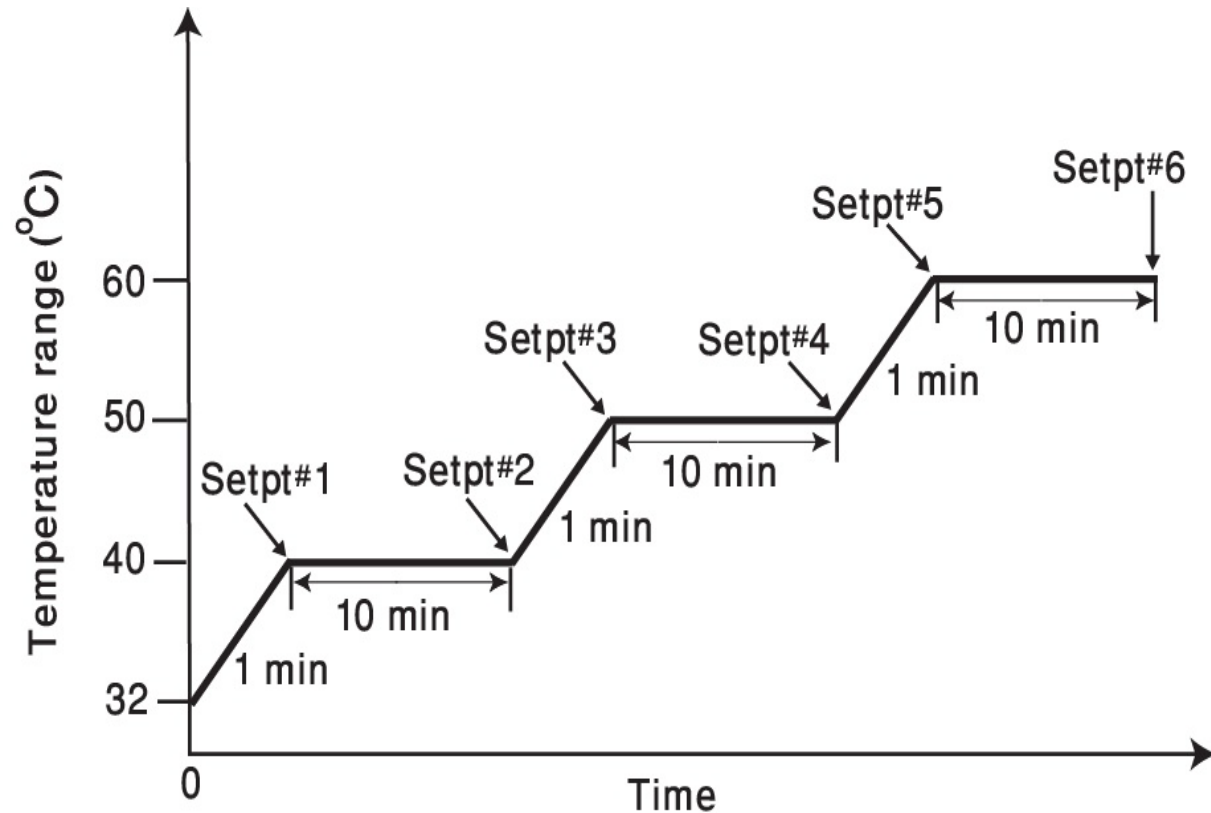
Temperature measurement

- ▶ PID constants

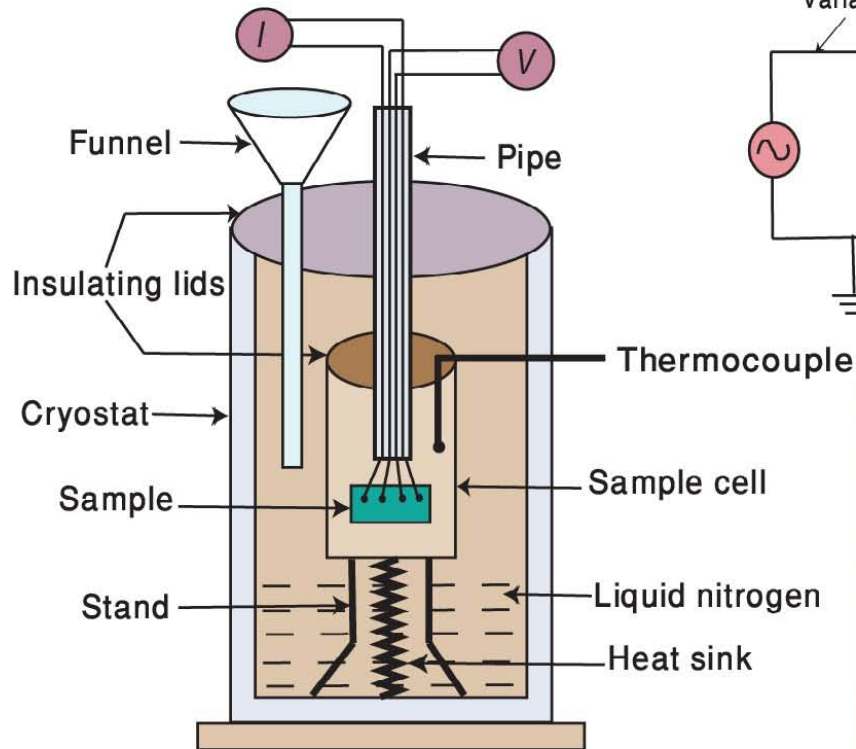
- ▶ $P=0.5$,

- ▶ $I=1$,

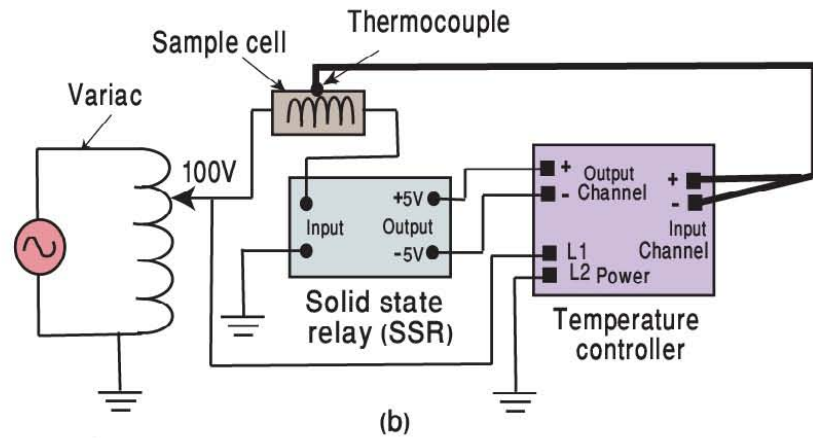
- ▶ $D=1$.



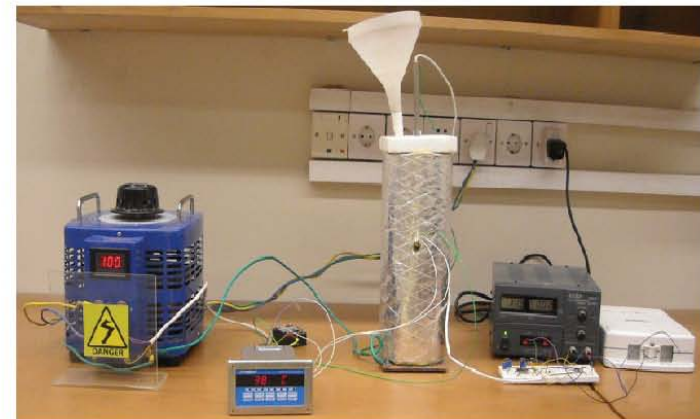
Experimental setup



(a)



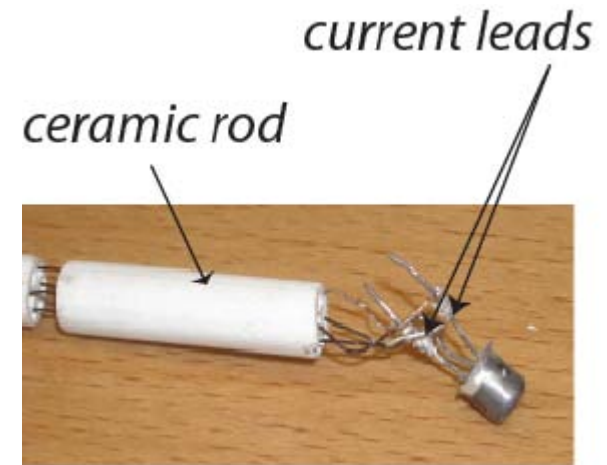
(b)



(c)

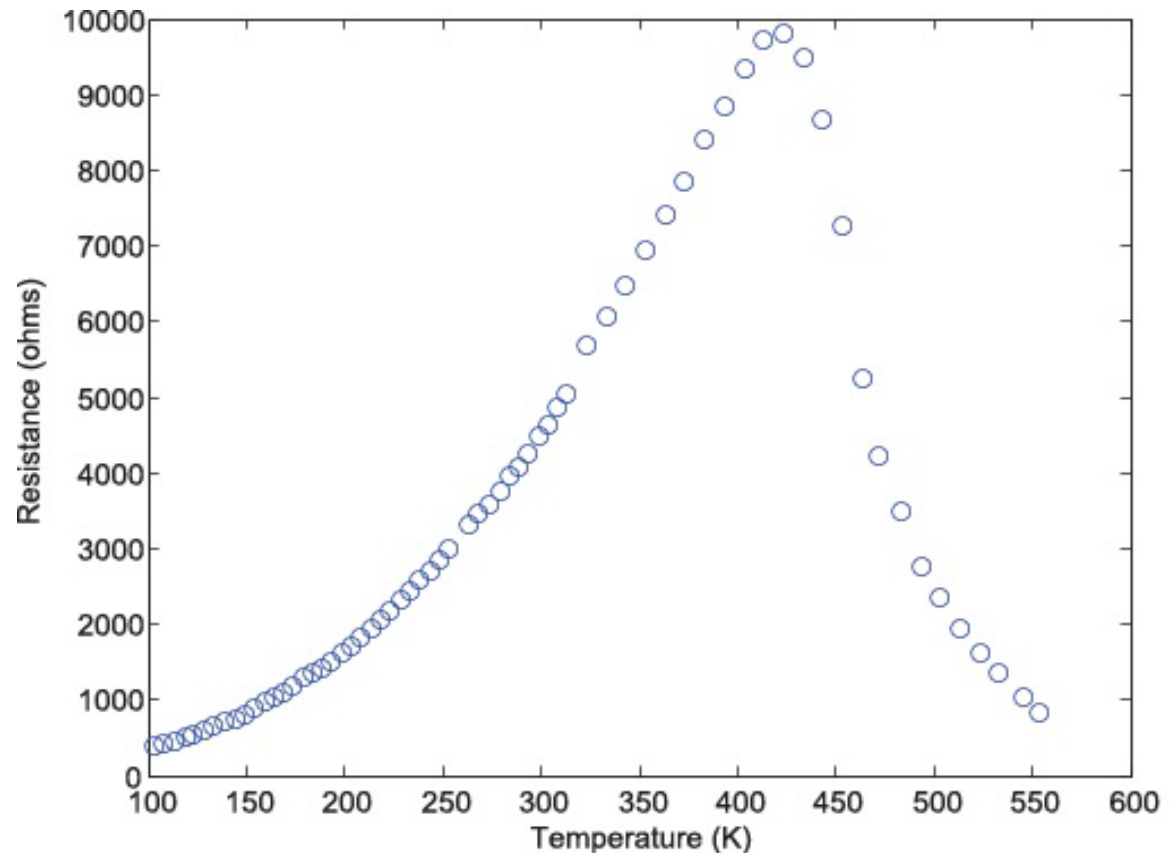
UJT sample (doped silicon)

- ▶ Constant current of $100\ \mu\text{A}$
- ▶ Resistance values in the temperature range of $-150\ ^\circ\text{C}$ to $250\ ^\circ\text{C}$.
- ▶ Calculate band gap from the intrinsic region data.
- ▶ Calculate the temperature coefficient of the carriers mobility from the extrinsic region data.



UJT sample (doped silicon)

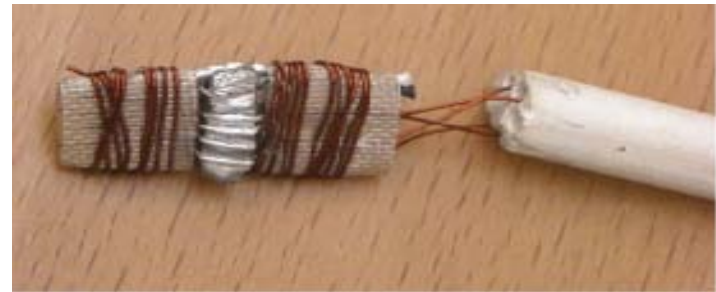
- ▶ $E_g = 1.03 \text{ eV}$
- ▶ $\alpha = 2.5$



Resistance versus temperature plot of UJT

Germanium sample

- ▶ Constant current of 10 mA.
- ▶ Resistance values from room temperature to 150°C.
-
- ▶ Resistance is calculated through 4-probe method.
- ▶ Calculate band gap from the intrinsic region data.



Germanium sample

► $E_g = 0.77\text{eV}$

